IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Kenichi SHIRAISHI

Application No.: New U.S. National Phase of PCT/JP2005/001827

Filed: August 1, 2006

Docket No.: 128985

For:

EXPOSURE APPARATUS, DEVICE MANUFACTURING METHOD,

MAINTENANCE METHOD, AND EXPOSURE METHOD

PRELIMINARY AMENDMENT

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Please consider the following:

Amendments to the Specification; and

Remarks.